Abstract

The invention relates to a method for configuring a double- or single-sided processing machine with a preferably annular first working disk and a preferably annular counterbearing element, wherein the first working disk and the counterbearing element can be driven rotationally relative to each other, and wherein a preferably annular working gap for double-sided or single-sided processing of flat workpieces, preferably wafers, is formed between the first working disk and the counterbearing element, comprising the following steps:

a) a control apparatus actuates means for step-by-step or continuously deforming the first working disk between a concave shape and a convex shape,

b) during the step-by-step or continuous deformation of the first working disk, the working gap width at at least two radially spaced apart locations of the first working disk is measured step-by-step or continuously and the measurement values are given to the control apparatus,

c) the control apparatus determines a measurement value average in each case from the measurement values of the working gap width at the at least two radially spaced apart locations,

d) the control apparatus determines the minimum of the measurement value averages and, on the basis of the determined minimum, specifies a target value for the means for deforming the first working disk as a starting value for the processing of flat workpieces in the double- or single-sided processing machine.

The invention also relates to a double- or single-sided processing machine.

Fig. 1